

FIG. 4

Isolation

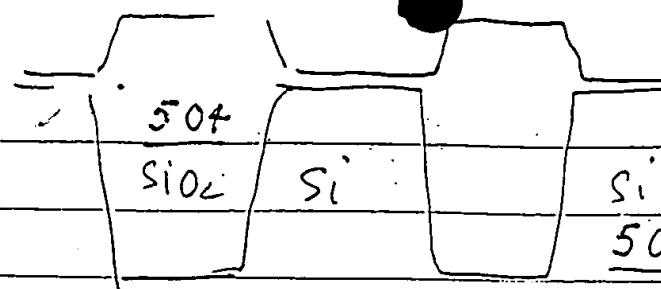


FIG. 5

VT and well implants

Channel stop

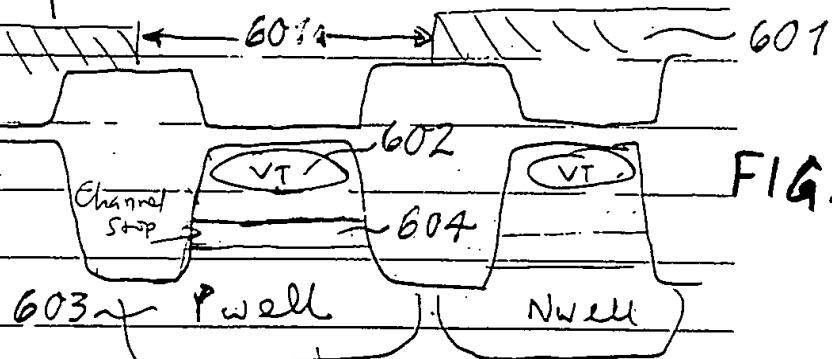


FIG. 6

Gate definition

603+Pwell

Nwell

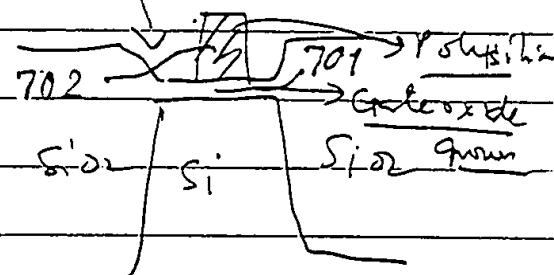


FIG. 7

NMOS & PMOS LDD & pocket implants

Halo

Spacers + SD imp

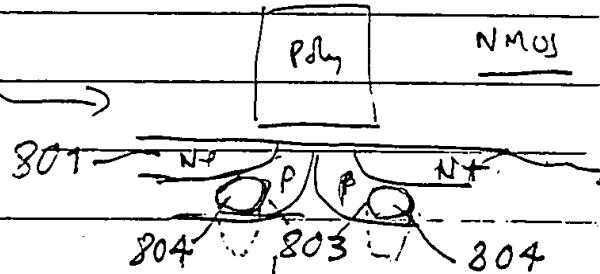


FIG. 8

Silicide formation

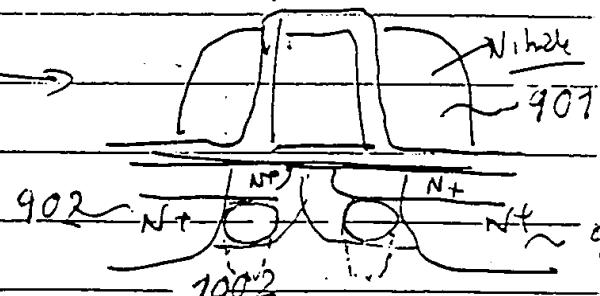


FIG. 9

PMD + Contact formation

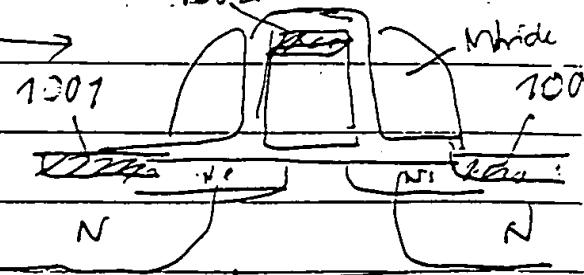


FIG. 10

Metal deposition pattern

N